

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Scott G. Meikle et al.

Title: METHOD OF DEPOSITING TUNGSTEN NITRIDE USING A SOURCE GAS COMPRISING SILICON

Docket No.: 303.444US5  
Filed: December 5, 2001  
Examiner: Ginette Peralta  
Customer No.: 21186



Serial No.: 10/004714  
Due Date: September 3, 2003  
Group Art Unit: 2814  
Confirmation No.: 2321

**MS Non-Fee Amendment**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

- ☒ A return postcard.
- ☒ An Response under 37 CFR 1.111 (13 Pages).

Please consider this a **PETITION FOR EXTENSION OF TIME** for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.  
Customer Number 21186

By: Marvin L. Beekman  
Atty: Marvin L. Beekman  
Reg. No. 38,377

**CERTIFICATE UNDER 37 CFR 1.8:** The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: MS Non-Fee Amendment, Commissioner for Patents, P.O.Box 1450, Alexandria, VA 22313-1450, on this 3rd day of September, 2003.

Amy Moriarty  
Name

Amy Moriarty  
Signature

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A. Customer Number 21186  
(GENERAL)

S/N 10/004714

PATENT

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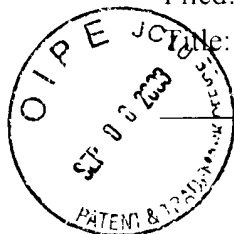
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RESPONSE UNDER 37 CFR § 1.111

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Applicant has reviewed the Office Action mailed on June 3, 2003.

10/004714-1 INCOM